



1443A/PTO Rev. 10/95		U.S. Department of Commerce Patent and Trademark Office		Complete If Known	
<b>LIST OF PRIOR ART CITED BY APPLICANT</b>  (use as many sheets as necessary)				Application Number	10 / 784, 669
				Filing Date	02/23/04
				First Named Inventor	Fengyan Zhang
				Group Art Unit	
				Examiner Name	
Sheet	1	of	1	Attorney Docket No.	SLA.0642

U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No. <sup>1</sup>	U.S. Patent Document Kind Number	Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YY	Pages, Columns, Lines, Where Relevant Passages or Figures Appear
		6,288,420		Zhang et al.	09-11-01	
		6,236,113		Zhang et al.	05-22-01	
		6,190,963		Zhang et al.	02-20-01	

FOREIGN PATENT DOCUMENTS								
Examiner Initials	Cite No. <sup>1</sup>	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YY	Pages, Columns, Lines, Where Relevant Passages or Figures Appear	T <sup>2</sup>
		Office <sup>3</sup> Code <sup>3</sup>	Number <sup>4</sup>	Kind				

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, country where published, source.	T <sup>2</sup>
		KIJIMA ET AL., Preparation of Bi <sub>4</sub> Ti <sub>3</sub> O <sub>12</sub> thin films on Si (100) using Bi <sub>2</sub> SiO <sub>5</sub> buffer layer and its electric characterization, J. Appl. Phys. Vol 37, Pt 1, 9B, 5171 (1998)	
		NAKAMURA ET AL., Preparation of C-axis-oriented Bi <sub>4</sub> Ti <sub>3</sub> O <sub>12</sub> thin films by metalorganic chemical vapor deposition, Jpn. J. Phys. Vol. 32, 4086 (1993)	

Examiner Signature		Date Considered	12/31/04
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Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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